

## Nanolab Equipment Responsibility List

| Equipment/Task       | Primary | Secondary | Area       |
|----------------------|---------|-----------|------------|
| Parylene Coater      | Huynh   | Hoc       | Deposition |
| STS Multiplex PECVD  | Huynh   | Tom       | Deposition |
| Unaxis PECVD         | Huynh   | Tom       | Deposition |
| NanoCamb ALD         | Wilson  | Max       | Deposition |
| UltraTech Plasma ALD | Wilson  | Max       | Deposition |
| BMR HiDep            | Huynh   | Tom       | Deposition |

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|-------------------------|---------|---------------|----------|
| Matrix 105 Stripper     | Hoc     | Tom           | Dry Etch |
| Oxford 80 RIE           | Tom     | Bo Chao/Hoc   | Dry Etch |
| STS AOE Etcher          | Tom     | Bo Chao/Huynh | Dry Etch |
| Technics RIE            | Tom     | Hoc           | Dry Etch |
| Tegal Plasma Stripper   | Hoc     | Huynh         | Dry Etch |
| Unaxis DRIE             | Tom     | Bo Chao/Huynh | Dry Etch |
| Unaxis fast DRIE DSE II | Tom     | Bo Chao/Huynh | Dry Etch |
| Unaxis C12 Etcher       | Tom     | Bo Chao/Huynh | Dry Etch |
| XeF2 Etcher             | Tom     | Bo Chao/Hoc   | Dry Etch |
| Ulvac Glass Etcher      | Tom     | Joe           | Dry Etch |
| FEi Nova 600 FIB        | Noah    | Wilson        | Dry Etch |

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|-------------------------|---------|-----------|----------|
| Guardian Burn Box       | Max     | Wilson    | Facility |
| Sensidyne Toxic Gas Sys | Wilson  | Tom       | Facility |
| DI Water                | Brian   | Hoc       | Facility |
| Nitrogen Tank           | Brian   | Max       | Facility |
| Gas Cabinets & Controls | Tom     | Wilson    | Facility |
| Oxygen Dewars           | Brian   | Max       | Facility |
| Lab Air/HVAC            | Hoc     | Max       | Facility |
| Chemical Scrubbers      | Wilson  | Max       | Facility |

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|-------------------------|---------|-----------|---------|
| Logitech PM5 CMP        | Huynh   | Hoc       | Lapping |
| Logitech CDP            | Huynh   | Hoc       | Lapping |
| Buehler Cross-sectioner | Noah    |           | Lapping |

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|-------------------------|---------|-----------|--------|
| CHA Mark 40 - new       | Hoc     | Huynh     | Metals |
| CHA Mark 40 - old       | Hoc     | Huynh     | Metals |
| CVC 601 Sputter         | Hoc     | Huynh     | Metals |
| Sloan E-beam Evaporator | Hoc     | Huynh     | Metals |
| Denton Discovery        | Hoc     | Joe       | Metals |

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|---------------------------|-----------|-----------|------------|
| Acctng sys & Invoicing    | Jamie     | Brian     | Management |
| Interlock System          | Brian     | Mo        | Management |
| Lab Runner                | Brian     | Jamie     | Management |
| Orientation/Badging       | Max/Brian | Steve     | Management |
| Office Computers          | Brian     | Joe       | Management |
| Inventory/orders etc.     | Jamie     | Students  | Management |
| Garments                  | Jamie     | Students  | Management |
| Web Site/Brochures/Maps   | Noah      | Brian     | Management |
| Lab Inspections/EHS Intfc | Wilson    | Max       | Management |

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| Student Supervision    | Max     | Steve/Brian | Management |
| New Customer/Tours etc | Tom     | Wilson      | Management |

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|------------------------------|---------|-----------|-----------|
| Dektak 6/8                   | Hoc     | Joe       | Metrology |
| EDX SEM attachment           | Hoc     | Noah      | Metrology |
| Flexus 2320A Stress          | Huynh   | Brian     | Metrology |
| Hitachi SEM                  | Noah    | Tom       | Metrology |
| M & M Probe Station & HP4145 | Hoc     | Joe       | Metrology |
| Nanospecs                    | Wilson  | Max       | Metrology |
| CDE resistivity mapper       | Hoc     | Brian     | Metrology |
| Sci Filmtek 2000             | Wilson  | Brian     | Metrology |
| Sopra GES5 Ellipsometer      | Wilson  | Max       | Metrology |
| Veeco 3100 AFM               | Max     | Wilson    | Metrology |
| Veeco NT3300 Profiler        | Joe     | Brian     | Metrology |
| Denton II SEM coater         | Hoc     | Noah      | Metrology |

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|--------------------|---------|-----------|-----------------|
| Nil 6 Nanostamper  | Joe     | Brian     | Nanolithography |
| NIL 6 Bond Aligner | Joe     | Brian     | Nanolithography |

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|-----------------------|---------|-----------|-------|
| Headway Spin Coaters  | Brian   | Max       | Photo |
| Hot Plates            | Max     | Wilson    | Photo |
| Ovens                 | Max     | Wilson    | Photo |
| Suss MA6 Aligners     | Tom     | Brian     | Photo |
| Suss SB6 Bonder       | Huynh   | Joe       | Photo |
| Heidelberg MaskWriter | Joe     | Max       | Photo |
| VWR Vac Oven          | Brian   | Wilson    | Photo |

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|--------------------------|---------|-----------|-----------------|
| ModularProcess RTA-III-V | Wilson  | Tom       | Thermal Process |
| Modular Process RTA-Si   | Wilson  | Tom       | Thermal Process |
| Tystar 4 Stack Furnace   | Wilson  | Tom       | Thermal Process |
| Tystar Sinter/Anneal     | Wilson  | Tom       | Thermal Process |
| Tystar Hi-Temp Furnace   | Tom     | Wilson    | Thermal Process |

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|-------------------|---------|-----------|--------------|
| He Leak Detectors | Tom     | Hoc       | Vacuum Tools |
| Orbital Welder    | Tom     | Wilson    | Vacuum Tools |

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|------------------------|---------|-----------|-------------------|
| Fume Hoods-4 other     | Max     | Wilson    | Wet/Vapor Process |
| PFC Fume Hood          | Max     | Wilson    | Wet/Vapor Process |
| Porous Si Etcher       | Brian   | Joe       | Wet/Vapor Process |
| Yellow Room            | Max     | Wilson    | Wet/Vapor Process |
| Fumehoods              |         |           |                   |
| Chemical Waste Collect | Max     | Brian     | Wet/Vapor Process |
| HFVE                   | Brian   | Huynh     | Wet/Vapor Process |
| Tousimis CP Dryer      | Huynh   | Brian     | Wet/Vapor Process |